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<b>PAT. NO.</b>	<b>Title</b>
1 <a href="#">11,296,049</a>	<a href="#">Processing oven</a>
2 <a href="#">10,840,068</a>	<a href="#">Plasma spreading apparatus and method of spreading plasma in process ovens</a>
3 <a href="#">10,490,431</a>	<a href="#">Combination vacuum and over-pressure process chamber and methods related thereto</a>
4 <a href="#">10,319,612</a>	<a href="#">Method for the rapid processing of polymer layers in support of imidization processes and fan out wafer level packaging including effiecient drying of precursor layers</a>
5 <a href="#">10,147,617</a>	<a href="#">Method for the rapid processing of polymer layers in support of imidization processes and fan out wafer level packaging including efficient drying of precursor layers</a>
6 <a href="#">8,361,548</a>	<a href="#">Method for efficient coating of substrates including plasma cleaning and dehydration</a>
7 <a href="#">8,252,375</a>	<a href="#">Apparatus for the efficient coating of substrates including plasma cleaning</a>
8 <a href="#">7,727,588</a>	<a href="#">Apparatus for the efficient coating of substrates</a>
9 <a href="#">6,267,075</a>	<a href="#">Apparatus for cleaning items using gas plasma</a>
10 <a href="#">6,198,075</a>	<a href="#">Rapid heating and cooling vacuum oven</a>
11 <a href="#">4,597,736</a>	<a href="#">Method and apparatus for heating semiconductor wafers</a>

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